SIMULATION OF OXYGEN IMPLANTED DISTRIBUTION

FOR SOL STRUCTURE

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SOI structure is thought to be the solution of many submicron CNOS problems [1]. However, hitherto, the distribution profile of oxygen ions in single crystal silicon has not been simulated in the VLSI process simulators. In Simulated in the VLS1 process simulators, in this paper, we gives out the oxygen implanted distribution model based on the statistical method. Due to its accuracy and simplicity, it is especially available for the process simulators. Also this model can be expanded to the simulation of the distribution of other reactive ions, as well as nonreactive ions such

reactive ions, as well as non-con-as B, F and As. First, we discuss the relationship between the threshold dose *Dose* and implantation energy F(see Fig.1), where the *Dose* is a minimum

implantation dose value in a given E for forming buried oxide insulation layer. It can be expressed by Talor series to the third order of E that is :

$$Dose_{th} = \sum_{i=1}^{3} b(i) \cdot E^{i}$$
(1)

Where

 $b(1)=4.827 \times 10^{-3} b(2)=3.345 \times 10^{-5} b(3)=-1.075 \times 10^{-7}$ Second, a concentration-position relationship of oxygen ions implanted in silicon is presented using quasi-half-gaussian frequency function [2] which is written as :

$$f(x) = \frac{1}{\sqrt{\pi} \cdot \sigma_1 / 2 + (Rm_1 - Rm_2)^2 + \sqrt{\pi} \cdot \sigma_2 / 2}}$$

$$\begin{cases} exp\left(-\frac{(x - Rm_1)^2}{2 \cdot \sigma_1}\right) & x < Rm_1 \\ 1 & Rm_1 \leq x \leq Rm_2 \\ exp\left(-\frac{(x - Rm_2)^2}{2 \cdot \sigma_2}\right) & x > Rm_2 \end{cases}$$

$$(2)$$

The impurity ion concentration c(x) can be determined by : $c(x) = Dose \cdot f(x)$ 131

Fig.2 shows the results of using quasi-halfgaussian function to fit the experiment data from [3]. Table 1 shows the value of Rm $R_{\mathbf{m}_2}, \sigma_1, \sigma_2$ extracted from experiment curves [3].

The general relationship between anyone of $Rm_1, Rm_2, \sigma_1, \sigma_2$ and E, Dose is sought by applying linear regression statistical method. Rm, Rm, can be expressed as

$$Rm_{1,2} = A(1) \cdot E + A(2) \cdot E^2 + A(3) \cdot E^2 + A(4) \cdot Dose +$$

$$A(5) \cdot Dose^{2} + A(6) \cdot E \cdot Dose \qquad (4)$$

 σ_i , σ_j can be expressed as :

 $\sigma_{1,2} = B(1) + B(2) \cdot E + B(3) \cdot E^{2} + E(4) \cdot Dose + B(5) \cdot Dose^{2} + B(5) \cdot$ B(6) · E · Dose (5)

all coefficients A(i), B(i) and other detail information about statistical analysis are included in Table 2, where SQRENE = E^2 , CUBENE = E^2 , Source and the second 2.0, all of the preceding statistical creteria value indicates that our model is acceptable [4]. The comparision between the real distribution of oxygen ions [3] and our simulated value is given in Fig.3. Calculations show that the singular comparision accuracy of our model is within 4%

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Table 2 statistical analysis results of $(a)Rm_{1}$, $(b)Rm_{2}$, $(c)\sigma_{1}$, $(d)\sigma_{2}$.